

QUERY CONTROL FORM

RTIS USE ONLY

Application No. 18091338
Examiner-GAU ELms-2824

Prepared by M. RUSNA
Date 6-28-4
No. of queries 1

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|----------------------|------------------------|--------------------|--------------------|
| a. Serial No. | f. Foreign Priority | k. Print Claim(s) | p. PTO-1449 |
| b. Applicant(s) | g. Disclaimer | l. Print Fig. | q. PTOL-85b |
| c. Continuing Data | h. Microfiche Appendix | m. Searched Column | r. Abstract |
| d. PCT | i. Title | n. PTO-270/328 | s. Sheets/Figs |
| e. Domestic Priority | j. Claims Allowed | o. PTO-892 | t. Other |

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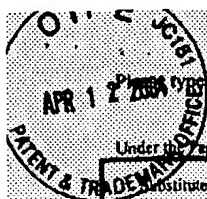
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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|------------------------|---------------------|
| Application Number | 10/091,338 |
| Filing Date | March 6, 2002 |
| First Named Inventor | Toru MITSUKI et al. |
| Group Art Unit | 2824 |
| Examiner Name | Bradley Smith |
| Attorney Docket Number | 0756-2448 |

Sheet 1 of 1

U.S. PATENT DOCUMENTS

| Examiner Initials ¹ | Cite No. ¹ | U.S. Patent Document | | Name of Patentee or Applicant of Cited Document | Date of Publication of Cited Document MM-DD-YYYY | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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| | | H. Koseki et al., <i>Recent Progress of Low Temperature Poly-Si Technology</i> , Electronic Display Forum, Pages 4-31 to 4-38 and English Translation, Pages 1-21, April 15, 1999. | |
| | | Kenji Sera et al., <i>Uniformity Improvement of Excimer Laser Crystallized Poly-Si Thin Film Transistors</i> , AM-LCD '96/IDM '96, Pages 85-88. | |
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| | | M. Fuse et al., <i>Performance of Poly-Si Thin Film Transistors Fabricated by Excimer-Laser Annealing of SiH₄ and Si₂H₆ Source Low Pressure Vapor Deposited a-Si Films With or Without Solid-Phase Crystallization</i> , Solid State Phenomena, Vols. 37-38, Pages 565-570, 1994. | |

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